

MICRO-ELECTRO-MECHANICAL SYSTEMS (MEMS)

Module-I 14 Lectures

Overview of MEMS and Microsystems. (Chapter 1 of Text Book 1)

Micromachining Techniques: Silicon as material for micromachining, Photolithography, thin film deposition, doping, wet and dry etching, surface and bulk micromachining, Wafer bonding, packaging. (Chapter 3 and Section 8.2 of Text Book 1, Chapter 2 of Text Book 2)

Module II 10 lectures

Microsystem Modeling and Design: Mechanics of deformable bodies, Energy method, Estimation of stiffness and damping for different micro-structures, Modeling of electromechanical systems, Pull-in voltage. (Section 4.1 to 4.3 and 6.2.2 of Text Book 1, Section 3.4 of Text Book 2)

Module III 15 Lectures

MEMS Applications: Mechanical sensors and actuators: Piezoresistive pressure sensors, MEMS capacitive accelerometer, Gyroscopes, Piezoelectric actuators. (Section 8.3 of Text Book 1 and Section 5.3 and 5.11 of Text Book 2)

Optical: Micro-lens, Micro-mirror, Optical switch (Section 7.5 to 7.7 of Text Book 2)

Radio frequency MEMS: Inductor, Varactor, Filter, Resonator. (Section 9.3 to 9.7 of Text Book 2)

Microfluidics: Capillary action, Micropumping, Electrowetting, Lab-on-a-chip. (Section 10.1 to 10.8 of Text Book 2)

Text Books:

1. G.K. Ananthuresh, K.J. Vinoy, S. Gopalakrishnan, K.N. Bhat and V.K. Atre: Micro and Smart Systems, Wiley India, New Delhi, 2010.
2. N.P. Mahalik: MEMS, Tata McGraw-Hill, New Delhi, 2007.

Reference Book:

1. T. Hsu: MEMS and Microsystems: Design and Manufacture, Tata McGraw-Hill, New Delhi, 2002.